

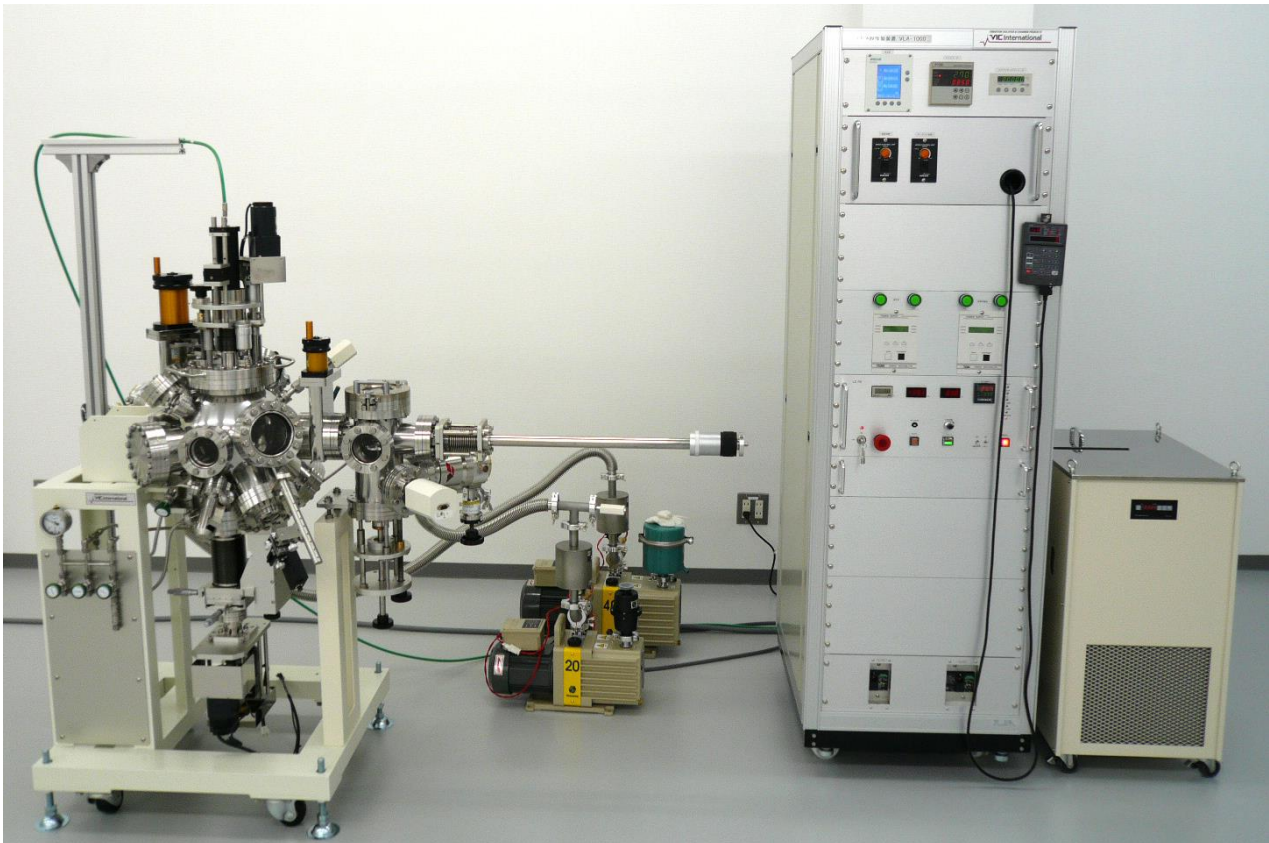
## PLD Equipment ( Pulsed Laser Deposition )

### Feature

- Selectable heater source of laser, lamp, or sheathed heater for 2 inches size substrate  
Substrate size can be changeable by discussion meeting
- Load-lock enables substrate and target to be changed in vacuum chambers
- Automatic operation of target rotation and swinging are available

### Optional:

Laser, Optical System, Laser Hood, etc.



PLD Equipment